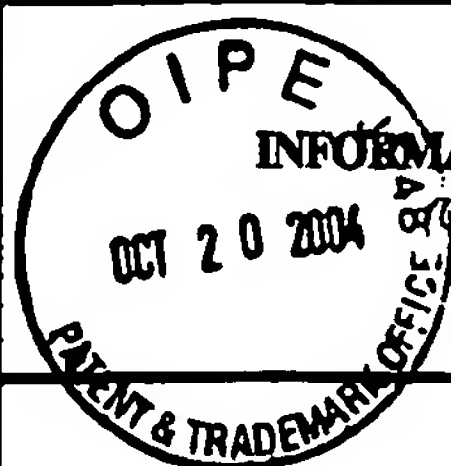


INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i> <div style="border: 1px solid black; border-radius: 50%; width: 100px; height: 100px; margin: 0 auto; display: flex; align-items: center; justify-content: center;"> <div style="writing-mode: vertical-rl; transform: rotate(180deg); font-size: 8px;">PATENT & TRADEMARK OFFICE</div> <div style="text-align: center;">OCT 20 2004</div> </div>				Docket Number (Optional) FIS920040210US1		Application Number 10/711,369		
				Applicant(s) Venigalla, et al.				
				Filing Date September 14, 2004		Group Art Unit 3723		
U.S. PATENT DOCUMENTS								
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
U.S. PATENT APPLICATION PUBLICATIONS								
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
J.A.		20040040217	03/04/2004	Takashina, et al.	—	—		
		20030211747	11/13/2003	Hedge, et al.	—	—		
		20030092271	05/15/2003	Jindal, et al.	—	—		
		20030047710	03/13/2003	Babu, et al.	—	—		
FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>								
J.A.		Prior Art - CHEMICAL PROCESSES IN GLASS POLISHING, Cook L.M., J. of Non-crystalline Solids, Vol. 120, pp 152-171.						
J.A.		A CMP MODEL COMBINING DENSITY AND TIME DEPENDENCIES, Taber H. Smith, et al., 1999 CMP-MIC conference proceedings.						
EXAMINER Jacob K. Achun Jr.				DATE CONSIDERED 7/13/05				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								



INFORMATION DISCLOSURE CITATION

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Docket Number (Optional)

FIS92004-0210US1

Application Number

10/711,369

Applicant(s)

Venigalla, et al.

Filing Date

September 9, 2004

Group Art Unit

3723

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

J.M.		CHEMICAL MECHANICAL PLANARIZATION OF MICROELECTRONIC MATERIALS, John Wiley and Sons, Inc., Wiley-Interscience publication, by Joseph M. Steigerwald, Shyam P. Murarka, Ronald J. Gutmann, year 1997, pages 140-147

EXAMINER

Jacob K. Ackon Jr.

DATE CONSIDERED

7/13/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.